



SEMI Standards Silicon Wafer Technical Committee

Europe Chapter

Munich ICM
Wednesday, Nov 13, 2019
14:00 – 16:00 CEST

AGENDA

Co-chairs: Werner Bergholz (Jacobs University), Fritz Passek (Siltronic) and Peter Wagner (Self)

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| 1. Welcome / Call to Order | 14:00 |
| 1.1. Introductions | |
| 1.2. Meeting Reminders (Membership Requirement, Antitrust and Intellectual Property Reminders, Effective Meeting Guidelines) | |
| 1.3. Agenda Review | |
| 2. Review and Approval of Previous Meeting Minutes (SEMI Staff) | 14:10 |
| 3. Liaison Reports (SEMI Staff) | 14:15 |
| 4. Staff Report (SEMI Staff) | 14:25 |
| 5. Ballot Adjudication | 14:30 |
| 5.1. Doc. 6574 Reapproval of SEMI M58-1109 (Reapproved 0614) ^E Test Method For Evaluating DMA Based Particle Deposition Systems And Processes | |
| 6. Subcommittee & Task Force Reports | 15:00 |
| 6.1. Int'l AWG TF | |
| 6.2. Int'l ASI TF | |
| 6.3. Int'l Polished Wafer TF | |
| 6.4. GCS | |
| 7. Old Business | 15:40 |
| 8. New Business | 15:45 |



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| 9. Action Item Review | 15:50 |
| 9.1 Open Action Items | |
| 9.2 New Action Items | |
| 10. Next Meeting and Adjournment | 16:00 |